

GURU GOBIND SINGH INDRAPRASTHA UNIVERSITY SECTOR 16C, DWARKA, NEW DELHI – 110078

GGSIPU/PUR/ Lab Equipments/USEM/2012-13/1721 To,

Phone No. 011-25302149 011-25302150 Dated: 22.03.2013

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NOTICE INVITING QUOTATION

Sealed item rate quotation is invited on behalf of Registrar, Guru Gobind Singh Indraprastha University, Sector 16 C, Dwarka, New Delhi from eligible manufacturers/distributors/authorized dealers for Supply & Installation of Lab. Equipments on buy back basis as per details given below:-

1.	Name of work:-	Supply & Installation of Gas Chromatograph and Atomic Absorption Spectrophotometer on buy back basis at Guru Gobind Singh Indraprastha University, Sector 16 C, Dwarka, New Delhi – 110078				
2.	Last date, time and venue for submission of quotation	05.04.2013 Upto 01.00p.m. in the office of In-Charge (Purchase), Ground Floor, Library Block, GGSIPU, Sector 16 C, Dwarka, New Delhi – 110078				
3.	Date, time and venue for opening of technical bid	05.04.2013 at 02.30p.m. in the office of Dean, USEM, GGSIPU, Sector 16 C, Dwarka, New Delhi – 110078				
4.	Financial bid shall be opened after evaluation of technical bid/time notified thereafter.					
5.	Time allowed	45 days (forty five days)				

The bids shall be submitted in two stages viz.(i) *Technical bid* (ii) *Financial bid*. Detailed specification of the item(s) to be supplied is placed at Annexure A

Eligibility:-

- 1. Certificate of Authorized dealership/distributor/manufacturer. (in case of manufacturer, they will self certify so. Authorized dealers/distributor shall attach attested copies of dealership/distributorship certificates issued by the manufacturer)
- 2. Undertaking by the agency in its Letterhead that:
 - a. An affidavit on Rs.10/- (non-judicial stamp paper) declaring that the bidder/ organization has not been blacklisted/debarred by any of the Central/State Government/Departments /Organizations/ Central or State PSU
 - b. That it will ensure fair trade practice.
 - c. An affidavit on Rs.10/- non judicial stamp paper that none of the GGSIPU employees including faculties having relation.
- 3. Should have valid registration with DVAT Deptt.
- 4. That the item(s) supplied under this contract shall have on-site and comprehensive warranty for 24 months from the date of supply.
- 5. All the specifications must be guaranteed with printed and authentic documents/catalogs.
- 6. Should have minimum average annual financial turn over of Rs.5 Crore during the last three years ending March 2012 duly certified by Chartered Accountant and a copy of Balance Sheet to be enclosed.
- 7. Vender/bidder should have experience of at least three year for selling of the above mentioned items. The Manufacturer should have an authorized service centre in Delhi or NCR should have executed at least 10 nos. of similar Supply of Lab Equipment for any public educational institutions including University, public sector undertakings, Govt. departments (central or state) or public research institutes in India for the financial year 2011-12 details of the works order attached with technical bid. This should be certified by an officer of the client organization not below the rank of Executive Engineer/Director/ Administrative Officer on their letter-head.

- 8. The bidder should quote the rate inclusive of all taxes & levies (including import duties, if any) as well as cost of transportation & installation at the GGSIP University at Dwarka for each items as per detailed specifications given in Financial Bid. Incomplete quote shall be summarily rejected.
- 9. Foreign manufacturers should quote the price up to FOR department.
- 10. The bidder shall quote unit rate in INR/USD/EURO/British Pound as the case may be, both in word and figures in the Financial Bid only. No alterations in the form of tender, in the schedule of quantities or additions etc. shall be permitted. In case of difference between the rates of items written in figures and in words, the rates of items written in words shall be taken as correct. No changes in unit rates shall be allowed. The rates quoted in schedule quantity are for finished and completed items and no extra amount for carting or transporting material, labour etc. shall be paid unless specifically so mentioned or provided for in tender. The rates should be inclusive of all leads and lifts for all materials in the completed items and also include all taxes, duties, royalties etc. including Work Contract Tax, labour cess, ESI, EPF etc. as applicable. No extra payment on this account will be made.
- 11. Custom duty and excise charges /duty shall be mentioned separately, if any, as University is exempted from customs duty. During clearance, the copy of the certificate will be provided.
- Note: Other important documents needed at the time of clearance should be submitted along with the bid.
- 12. Quoted rate should be offered for Imported Goods.
- 13. The bidder shall quote unit rate in INR/USD/EURO/British Pound as the case may be, both in word and figures in the Financial Bid only. <u>Exchange rate on the date of opening of financial bid will be applicable for the purpose of comparison as well as final payment</u>. Import items should be quoted as per performa invoice by the principals.
- 14. All items must be quoted, the total order will be "<u>treated as a package</u>" and lowest bidder will be considered as an average of all items including buy back prize.
- 15. The interested bidder can inspect the existing equipment on buy-back basis in the office of the Dean, USEM, A-Block, Sector-16C, Dwarka, New Delhi-110078 between 10:00 AM to 04:00 PM on all working days.
- 16. Original bill of entry must be provided.
- 17. Onsite training after installation will be imparted for five working days without any additional cost.

Terms & Conditions:-

- (1) The bidder shall place his bids in two separate envelops marked "Technical Bid" and "Financial bid". All documents in support of eligibility as well as another envelop containing DD/Pay order for EMD shall be placed in the envelope marked "Technical Bid". The offered rates shall be placed in the envelop marked "Financial bid". Both these bids should be superscribed with name of work and shall be placed in a third envelop which shall be superscribed "Quotation for Supply & Installation of Gas Chromatograph and Atomic Absorption Spectrophotometer at Guru Gobind Singh Indraprastha University, Sector 16 C, Dwarka, New Delhi 110078.
- (2) Bids without EMD will be summarily rejected.
- (3) Conditional Bids will be summarily rejected.
- (4) Bids received after due date & time shall be summarily rejected.
- (5) The "Financial bid" of those bidders whose technical bids have qualified will only be opened.
- (6) Rate must be quoted in Indian Rupees only net in figures & words inclusive of taxes, levies, cartage handling, loading, unloading etc.
- (7) Delivery :- F.O.R. GGSIP University, Sector 16 C, Dwarka, New Delhi
- (8) Consignment shall be dispatched by the Forwarding Agent and freight and custom duty etc. shall be paid by the Agency (bidder) for subsequent reimbursement by the University. University will provide the custom duty exemption certificate.
- (9) Delivery period: 45 days from the date of supply order.
- (10) The EMD of unsuccessful bidders shall be refunded immediately.
- (11) The successful bidder have to submit a Performance Security Deposit @ 10% of the quoted value in the form of Demand Draft/Pay order drawn in favour of Registrar, GGSIPU, Delhi within 7(seven) days of the communication accepting the bid. EMD shall be adjusted toward Performance Security Deposit. The Performance Security Deposit shall be refunded without interest after completion of the guarantee period of 24 months.
- (12) In case the successful bidder fails to deposit the Performance Security within the stipulated 7 (seven) days of the communication accepting the bid, the EMD shall be forfeited to GGSIP University absolutely.
- (13) In case the successful bidder fails to supply the item(s) within the delivered period, a sum equal to 0.5% of the contract price per week or part thereof until the actual delivery subject to maximum of 10% of the value of supply order shall be deducted.
- (14) The payment will be made after delivery and satisfactory installation of the equipment.
- (15) Taxes etc., if any, leviable shall be deducted at source.
- (16) The validity of the bid will be 120 days from the date of opening of financial bids. During the validity period, the successful bidder shall not be allowed to withdraw. In case of withdrawal, the EMD shall be forfeited to

GGSIP University absolutely and no claim shall be admitted in this regard. Such bidder shall not be allowed to participate in the re-quotation process.

- (17) The rates of successful bidder will be valid for 12 months from the date of issue of letter of acceptance.
- (18) University reserves the right to reject any or all the bids or accept them in part or reject the lowest bid without assigning any reason.
- (19) Unauthorized substitution or materials delivered in error of wrong description or quality or supplied in excess quantity or rejected goods shall be returned to the bidder at bidder's cost & risk.
- (20) The successful bidder shall make all arrangements towards safe and complete delivery at the designated location indicated in the supply order. Such responsibility on the part of the bidder will include taking care of insurance, freight, state level permits etc. as applicable.
- (21) In case of any dispute relating to meaning, scope, manufacturing, operation or effect of this contract or the validity or the breach thereof, University and the contractor shall make every effort to resolve amicably by direct discussion/negotiation.
- (22) In case the dispute cannot be settled amicably within 30 days of the raising of dispute by either party, either party may seek settlement of the dispute by arbitration in accordance with the provisions of the Arbitration & Conciliation Act, 1996 and the award made in pursuance thereof shall be binding on all the parties. The sole arbitrator shall be appointed by Vice Chancellor, GGS Indraprastha University.
- (23) The performance under this contract shall not be stopped for any reason whatsoever during the said dispute/proceedings unless the contractor is specifically directed to do so by the University.
- (24) The venue of arbitration proceedings shall be Delhi/New Delhi. The language of proceedings shall be English. The law governing the substantive issues between the parties shall be the Laws of India. All disputes are subject to Jurisdiction of Delhi Courts only.
- (25) It is also a term of the contract that if any fee payable to the arbitrator, shall be paid equally by both the parties. It is also a term of the contract that the arbitrator shall be deemed to have entered in the reference on the date he/she issues notice to both the parties calling them to submit their statement of claims and counter statement of claims.
- (26) Force Majeure.

For purpose of this clause, 'Force Majeure' means an event beyond the control of the contractor and not involving the contractor's fault or negligence and not foreseeable. Such events may include, but are not limited to, acts of the University either in its sovereign or contractual capacity, wars or revolutions, fires, floods, epidemics, quarantine restrictions and freight embargo.

If a Force Majeure situation arises, the contractor shall promptly notify the University in writing of such conditions and cause thereof. Unless otherwise directed by the University in writing, the contractor shall continue to perform its obligations under this contract as far as reasonably practical and shall seek all reasonable alternative means for performance not prevented by Force Majeure event.

(Col. (Retd.) P.M. Bedekar) In-charge (Purchase) Financial/Commercial Bid – 'Separate Envelope'. No cutting and overwriting condition shall be permitted.

S. No.	Name of items & Specifications	Qty.	EMD (Rs.)	Unit Price in figure (inclusive taxes)	Unit Price in words (inclusive taxes)
1.	 SPECIFICATION FOR ATOMIC ABSORPTION SPECTROMETER Fully automatic Atomic Absorption Spectrometer, incorporating all spectrometer and atomizer components in a single instrument. The instrument should have following features: Real Time Double Beam optical Spectrometer with Wavelength Range 190 - 900 nm or better. Diffraction grating used as dual blazed with ruling density of 1800 lines/mm or better. To be fitted with deuterium background correction with automated monochromatic and slits. Air purging facility required. Spectral bandwidths of 3 different types programmable through software using auto slit selection mode. System should have 6-8 Lamps position Automatic Turret with computer controlled lamp selection Built-in power supply for EDL/SUPER/ULTRA Lamps to enhance capability. Lamps should be as per GCP compliance The Detector used shall be Solid-State Detector/ Photomultiplier Tube. Total Gas Flow Control System maintains gas flows (Ratio of fue/oxidant) at set levels to ensure excellent Flame stability and performance. Lamps should automatically switch off at the end of analysis. Gas control: Fully Programmable gas control system with automatic setting of gas flows. Should have fast response solenoid valve for rapid regulation and setting of selected gas flow. Safety system: There should be adequate safety measurement such as separate ignite/flame-off buttons, internal gas connections made automatically, flame shields and protection against heat and UV radiation. External adjustment of all burner and spray chamber controls. Violation of any safety interlock should prevent flame ignition or should extinguish existing flame. Automatic Gas Flow adjustment during change over between air CPH and N20. 	01	60000/		

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		• A warranty of 3 years extendable for 2 more years			

	including spares (consumables and non consumables) and				
	workmanship to be quoted.				
•	Future upgradability with other detectors like				
	ECD,NPD and TCD from the same vendor.				
•	Upgradability to MS from the same vendor.				
	Total Amount in (Rs.) inclusive all taxes				

RATES OF THE ITEMS ON BUY BACK BASIS

S.No.	Name of items & Specifications and make	Qty.	Reserved Pries in Rs.	Quoted Rate in Rs.	
1.	SPECIFICATION FOR	01	245000/-		
	ATOMIC ABSORPTION SPECTROMETER, Model				
	Analyst 400 by Perkin Elmer Date of Purchase				
	i.e.14.06.2001				
2.	SPECIFICATIONS FOR GAS CHROMATOGRAPH,	01	195000/-		
	Model GC6890N/ Agilent Technologies date of Purcha				
	i.e.26.096.2011				
	Total Amount in (Rs.) inclusive of transportation				

All items must be quoted, the total order will be "<u>treated as a package</u>" and lowest bidder will be considered as an average of all items including buy back prize.

Date and time of opening of Financial Bid shall be intimated after evaluation of Technical Bid of Eligible agencies/bidders.

(Col. (Retd.) P.M. Bedekar) In-charge (Purchase)